

Form PTO-1449

INFORMATION DISCLOSURE CITATION

Docket Number (Optional)

NIM-01301

Application No.

09/804,499

IN AN APPLICATION

(See several sheets if necessary)

NOV 06 2003

Applicant Yoshitaka YOKOYAMA

Filing Date March 12, 2001

Group Art Unit 2815

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JN	AA 5,760,419	06/02/1998	Rashit F. Nabiev, et al.			
	AB 5,216,237	06/01/1993	Simon Ritchie, et al.			
	AC 4,821,273	04/11/1989	Nobuo Hori			
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
JN	AL EP 0 390 525 A2	10/03/1990	EPO				
	AM EP 0 818 857 A1	01/14/1998	EPO				
	AN PCT/US98/25142	11/24/1998	PCT				
	AO 58 056539 A	04/04/1983	Japan			(English Abstract)	
	AP 2000 56185 A	02/25/2000	Japan			(English Abstract)	
	AQ						

OTHER DOCUMENTS

(Including author, Title, Date, Pertinent Pages)

JN	AR	T. Niemi, et al.: "Temperature-Tunable Silicon-Wafer Etalon for Frequency Chirp Measurements," Microwave and Optical Technology Letters, John Wiley & Sons, Inc., NY, NY, US, vol. 20, No. 3, February 5, 1999, pages 190-192; ISSN: 0895-2477/99					
	AS						
	AT						
	AU						
	AV						
	AW						
	AX						
	AY						
	AZ						

EXAMINER

Bseptloguy

DATE CONSIDERED

2/3/04

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE